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|--|---|----------------------------------|--|--|--------------------------------|--|
| SERIAL NUMBER 10/587,039 | FILING or 371(c) DATE 07/24/2006 RULE | CLASS 117 | GROUP ART UNIT 1792 | ATTORNEY DOCKET NO. 061063-0356139 | | |
| APPLICANTS Masataka Hourai, Saga-shi, JAPAN; Wataru Sugimura, Saga-shi, JAPAN; Toshiaki Ono, Saga-shi, JAPAN; ** CONTINUING DATA ***** This application is a 371 of PCT/JP05/15346 08/24/2005 ** FOREIGN APPLICATIONS ***** JAPAN 2004-246017 08/25/2004 JAPAN 2005-163152 06/02/2005 JAPAN 2005-239529 08/22/2005 ** IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** 04/02/2007 | | | | | | |
| Foreign Priority claimed <input checked="" type="checkbox"/> Yes <input type="checkbox"/> No 35 USC 119(a-d) conditions met <input checked="" type="checkbox"/> Yes <input type="checkbox"/> No Verified and /FELISA CARLA HITESHEW/ Acknowledged Examiner's Signature | <input type="checkbox"/> Met after Allowance Initials | STATE OR COUNTRY JAPAN | SHEETS DRAWINGS 12 | TOTAL CLAIMS 8 | INDEPENDENT CLAIMS 2 | |
| ADDRESS PILLSBURY WINTHROP SHAW PITTMAN, LLP P.O. BOX 10500 MCLEAN, VA 22102 UNITED STATES | | | | | | |
| TITLE Silicon wafer, method for manufacturing the same and method for growing silicon single crystals | | | | | | |
| FILING FEE RECEIVED 900 | FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following: | | <input type="checkbox"/> All Fees | | | |
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